

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re Patent Application of)
 Shunpei YAMAZAKI et al.)
 Serial No. 09/362,192)
 Filed: July 28, 1999) Group Art Unit: 2815
 For: SEMICONDUCTOR DEVICE) Examiner: D. Hardy
 HAVING SEMICONDUCTOR)
 CIRCUIT COMPRISING)
 SEMICONDUCTOR ELEMENT)
 AND METHOD FOR)
 MANUFACTURING THE SAME)

CERTIFICATE OF MAILING *Amata*

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AMENDMENT AND RESPONSE TO ELECTION REQUIREMENT

Honorable Assistant Commissioner for Patents
 Washington, D.C. 20231

Sir:

In response to the Office Action of September 21, 2000, please amend the subject application as follows:

IN THE CLAIMS:

Cancel claims 1-28 without prejudice to applicants' right to file a division application with respect thereto.

Please add new claims 45-59:

a 1 Sub
 7/45. A method for manufacturing a semiconductor device comprising steps of:
 forming an initial semiconductor film formed over a substrate;
 subjecting said semiconductor film to oxygen plasma; and

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01-PP:116
 02-PP:102

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